

IN THE CLAIMS:

1-3. Cancelled.

4. (Currently amended) A plasma processing apparatus for carrying out a process with plasma generated by using an electromagnetic wave, comprising:

a component made of glass, which is transparent to said electromagnetic wave and is used for introducing said electromagnetic wave into a chamber in which said plasma is generated,

a cover component including a plurality of openings, into which said glass component is fitted, and an antenna fixed to said cover component, wherein

said glass comprises:

a first glass phase consisting essentially of Si and O; and

a second glass phase consisting essentially of Si, Al, and O, wherein said second glass phase has 0.1-10 parts aluminum-containing oxide powder added to 100 parts quartz powder, wherein said first glass phase is substantially evenly dispersed in the second glass phase.

5. (Previously added) The plasma processing apparatus of claim 4, wherein the second glass phase has a mass ratio of Al to Si of at least 0.01.

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6. (Previously added) The plasma processing apparatus of claim 4, wherein said second glass phase has 1-5 parts aluminum-containing oxide powder added to 100 parts quartz powder.

7. (Previously added) The plasma processing apparatus of claim 4, wherein the quartz powder has a purity of at least 99.9%.

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